

BOC EDWARDS

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iH Series Drypumps

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for Better Process Results

Ist Choice for Vacuum Solutions









SEMICONDUCTOR INDUSTRY STANDARDS COMPLIANCE

The iH Series Drypumps comply with internationally recognized semiconductor industry standards: SEMI® S2 (Semiconductor Equipment and Materials International), ETL (Energy Technology Laboratories), which conforms to UL Standard 3101-1 and CE Mark (European Community Mark). BOC Edwards is a leading supplier of integrated process-enabling technologies, materials and services for semiconductor and Flat Panel Display (FPD) processes. Products include process gases, gas delivery systems, vacuum pumps, chillers, exhaust gas management, chemical blend and dispense systems, liquid abatement, and monitoring and control equipment. An extensive range of services includes tool component cleaning, equipment repair, and on-site materials and equipment support. BOC Edwards has over 100,000 pumps installed, supporting 200 mm and 300 mm fabs worldwide and operates in every major semiconductor manufacturing region. BOC Edwards is part of the BOC Group plc, which employs over 30,000 people and had annual sales in excess of \$8b in 2004.

BOC Edwards advanced semiconductor vacuum pumps have been field-proven to perform to the highest operating standards. Reliability and high performance are achieved by extending service life, improving uptime and increasing productivity, while minimizing footprint and cost of ownership.

The iH Series offers high reliability for difficult processes, such as PECVD and LPCVD, where particulate, condensable and corrosive by-products are present. iH dry pumps are available in a range of peak speeds, from 80 to 1800 m^3/h . iH 1800 dry pumps are specifically designed for high-throughput applications.

iH Series Benefits

Pumping Expertise and Leadership

BOC Edwards is the global market leader for advanced vacuum pumps, supplying over 60% of the pumps currently installed in 300 mm fabs. With more than 100,000 BOC Edwards dry pumps supplying vacuum on 200 mm and 300 mm processes, reliability has been proven.

Proven Design

The iH Series has been designed with cantilevered shafts and specially profiled rotors for better handling of particles. Reserve motor power also maximizes reliability on harsh-duty CVD applications. Corrosionresistant materials allow pumping of corrosive gases while higher operating temperatures provide ample margin to prevent gas condensation.

Low Cost of Ownership

The iH Series minimizes ownership costs through optimized utilities consumption and with no preventative maintenance required. High operating temperatures minimize the amount of N_2 dilution required and the absence of greased bearings eliminates the need for intervention between overhauls.



Optimized Footprint

The one-piece shaft eliminates the need for a motor coupling and a fifth pumping stage removes the need for a silencer and eliminates particle accumulation, both reducing the overall footprint.



Non-reactive-games used

A range of ATEX compliant pumping systems is available. Contact BOC Edwards for details.

Commine or reactive government

iH80 to iH1800 Series

The iH Series is the product of over 20 years dry vacuum pump expertise and field experience. iH dry pumps are the preferred pumps for most 300 mm production lines. iH pumps provide application-specific solutions for the full range of semiconductor fabrication processes.

The major OEMs recommend iH Series drypumps for harsh processes.

The optional Tool and Network Interface Modules (iTIM and NIM) allow control by any OEM tool and fabwide monitoring maximizes equipment availability.



IOC IDVUS

iH1800



iH1800 and iH1800HTX

The iH1800 dry pumps are designed to provide highthroughput pumping for harsh 300 mm process applications.

The iH1800HTX is specifically designed for processes such as 300 mm LPCVD Nitride, where higher operating temperatures are required to prevent process gas condensation.

iH Technical Data

iH80		iH600		iH1000		
	50 Hz	60 Hz	50 Hz	60 Hz	50 Hz	60 Hz
m³h-1	86	103	518	600	950	1000
cfm	51	61	305	353	560	589
I min [.]	1433	1717	8635	10000	15837	16670
mbar	3 x 10 ⁻²	I x 10 ⁻²	2 x 10 ⁻³	7 x 10⁴	2 x 10 ⁻³	I x 10 ⁻³
Torr	2.3 x 10 ⁻²	7.5 x 10 ⁻³	1.5 x 10 ³	5.3 x 10⁴	1.5 x 10 ⁻³	7.5 x 10⁴
Pa	3	I.	0.2	0.07	0.2	0.1
slm	4	4	4	4	4	4
	ISO63	ISO63	ISO I 00	ISO I 00	ISO 100	ISO I 00
	NW40	NW40	NW40	NW40	NW40	NW40
۱ h ^{.,}	120	120	240	240	240	240
I min [.]	2	2	4	4	4	4
kg	240	240	415	415	430	430
kW	2.4	2.7	3.1	3.4	3.5	3.8
kW	2.9	3.5	5.1	6.1	5.1	6.1
1	0.7	0.7	1.43	1.43	1.48	1.48
	m ³ h ⁻¹ cfm I min ⁻¹ mbar Torr Pa slm I h ⁻¹ I min ⁻¹ kg kW kW kW I	H 50 Hz m ³ h ⁴ 86 cfm 51 1 min ⁴ 1433 mbar 3 × 10 ² Torr 2.3 × 10 ² Torr 2.3 × 10 ² Pa 3 slm 4 ISO63 NVV40 1 h ⁻¹ 120 I min ⁴ 2 kg 240 kW 2.4 kW 2.9 I 0.7	50 Hz 60 Hz m³h¹ 86 103 cfm 51 61 lmin¹ 1433 1717 mbar 3 × 10² 1 × 10² Torr 2.3 × 10² 7.5 × 10³ Pa 3 1 slm 4 4 ISOG3 ISOG3 NW40 NW40 I h¹ 120 I min¹ 2 kg 240 kW 2.9 I 0.7	iH80 iH60 50 Hz 60 Hz 50 Hz mihi 86 103 518 cfm 51 61 305 Imini 1433 1717 8635 mbar 3 x 10 ² 1 x 10 ² 2 x 10 ³ Torr 2.3 x 10 ² 7.5 x 10 ³ 1.5 x 10 ³ Pa 3 1 0.2 sim 4 4 4 ISO63 ISO63 ISO100 NVV40 NVV40 NVV40 I hrii 120 120 240 I mini ¹ 2 2 4 kg 240 240 415 KW 2.4 2.7 3.1 KW 2.9 3.5 5.1 I 0.7 0.7 1.43	iH80 iH600 50 Hz 60 Hz 50 Hz 60 Hz m³h¹ 86 103 518 600 cfm 51 61 305 353 lmin¹ 1433 1717 8635 10000 mbar 3 x 10² 1 x 10² 2 x 10³ 7 x 10⁴ Torr 2.3 x 10² 7.5 x 10³ 1.5 x 10³ 5.3 x 10⁴ Pa 3 1 0.2 0.07 slm 4 4 4 4 ISO63 ISO100 ISO100 ISO100 NVv40 NVv40 NVv40 NVv40 NVv40 I min² 2 2 4 4 Igo 20 240 240 240 I min² 2 4 4 4 I min² 2 4 4 4 100 20 120 240 240 15 kg 240 240 415	iH80 iH600 iH10 50 Hz 60 Hz 50 Hz 60 Hz 50 Hz 50 Hz m³h ⁻¹ 86 103 518 600 950 cfm 51 61 305 353 560 lmin ⁴ 1433 1717 8635 10000 15837 mbar 3×10^2 1×10^2 2×10^3 7×10^4 2×10^3 Torr 2.3×10^2 7.5×10^3 1.5×10^3 5.3×10^4 1.5×10^3 Pa 3 1 0.2 0.07 0.2 slm 4 4 4 4 4 ISO63 ISO63 ISO100 ISO100 ISO100 NVV40 NVV40 NVV40 NVV40 NVV40 Imin ⁴ 2 2 4 4 4 kg 240 240 240 240 240 240 Imin ⁴

All figures are typical without gas ballast

Pumping Speed Curves - iH80 & iH600





Pumping Speed Curves - iH1000





iH Dimensions





iH600 & iH1000







- I INLET
- 2 OUTLET
- 3 AIR EXTRACTION PORT
- 4 INVERTER BOX (iH1000 only)
- A SIDE VIEW
- B PLAN VIEW



iH Technical Data

Specifications

iH160

iH1800/HTX

		50 Hz/60 Hz	50 Hz/60 Hz
• Peak speed	m³h-ï	165	1800
	cfm	97	1060
	l min⁻'	2,750	30,000
Ultimate vacuum	mbar	I x 10 ⁻²	I x 10 ⁻³
(with shaft seal purge only)	Torr	7.5 x 10 ⁻³	7.5 x 10⁴
	Pa	I.	0.1
• Typical shaft seal nitrogen flow	slm	4	4
Inlet connection		ISO63	ISO I 60
Outlet connection		NW40	NW40
 Typical cooling water flow at 	I h [.]	120	240
15psi pressure drop	I min ⁻¹	2	4
• Weight	kg	244	502
• Power input at ultimate	kW	3.1	4.1
 Rated motor power 	kW	5.0	7.0
• Oil capacity	I	0.85	1.6

All figures are typical without gas ballast

Pumping Speed Curves - iH160



Pumping Speed Curves - iH1800/HTX

50 Hz/60 Hz 10 10 Speed (m³ h⁻¹) 10 10 10° L 10² 10³ mbar 10 10 * 10 10 10 10-1 10⁵ Pa 10⁰ 10 ¹ 10³ 10² 10⁴ Pressure



iH Dimensions

Α

909 iH160 723 134 640 379 1 2 783 529 525 310 U 661 77 774









- INLET
- OUTLET
- AIR EXTRACTION PORT
- INVERTOR BOX SIDE VIEW
- PLAN VIEW

